

Modular Glovebox Systems Gas Purifier Units

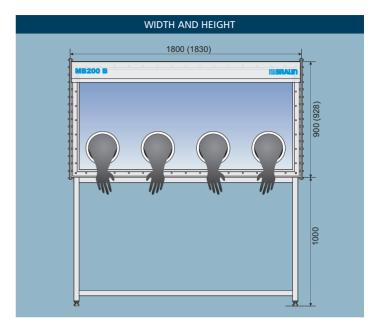


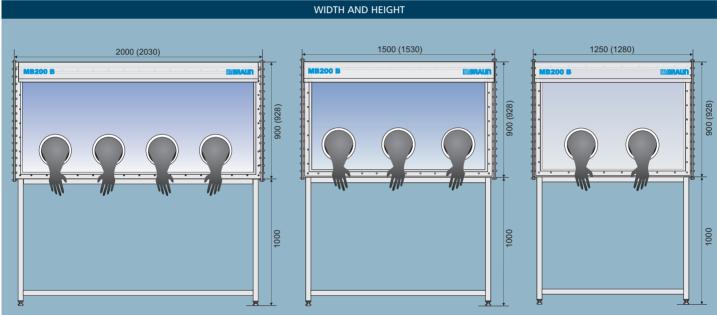
- Modular glovebox with screwed in flanged side panels
- Easy to extend or modify while keeping a flat work place
- Define your specific system with suitables gas purifier units
- Possibility to connect 2 gloveboxes directly or link them with an antechamber
- Large choice of antechambers
- Sensors dedicated to our application
- Feedthroughs to adapt your tools in the glovebox

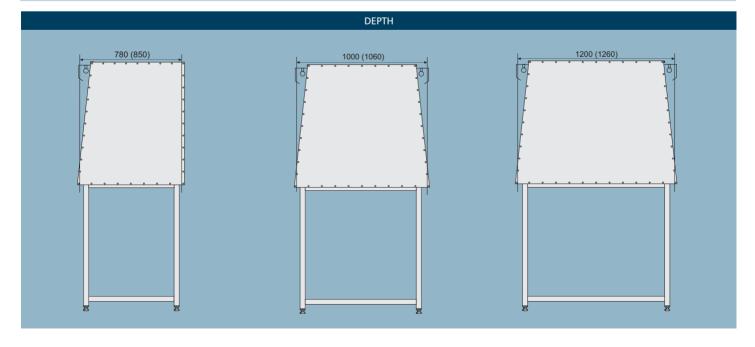
Modular Glovebox System Dimensions

DESCRIPTION	
Length / Depth (in mm)	Weight
1250/780	218 kg
1500/780	250 kg
1800/780	288 kg
2000/780	320 kg
1250/1000	265 kg
1500/1000	294 kg
1800/1000	344 kg
2000/1000	382 kg
1250/1200	293 kg
1500/1200	325 kg
1800/1200	378 kg
2000/1200	420 kg

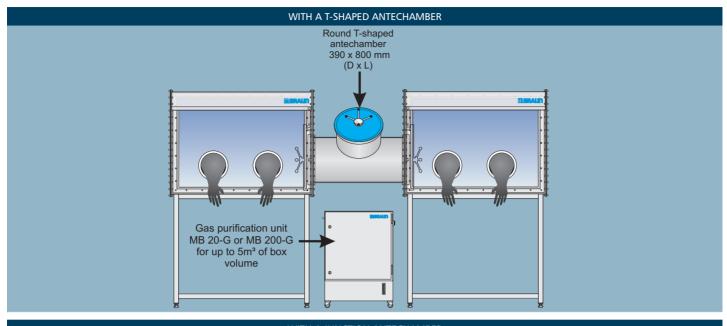
Technical note: Inner (and outer) dimensions in mm

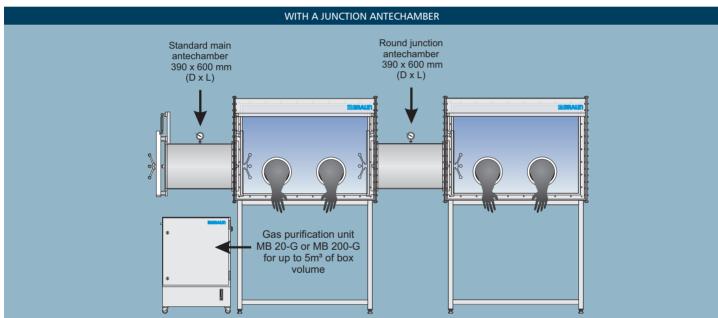


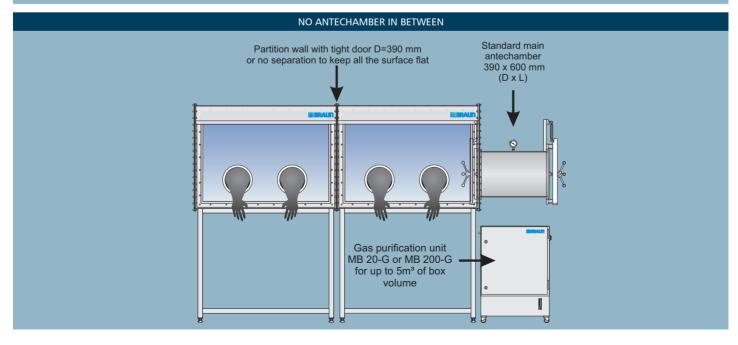




Several Solutions to Build your System







Gas Purifier Units











	MB-10-G	MB-20-G	MB-200-G	MB-300-G	MB-600-G	
Operation principle	Closed loop recirculation		WID 200 G	1410 300 G	WID COO C	
Attainable purity level	Moisture < 1 ppm, Oxygen < 1 ppm					
Recommended enclosure volume	Up to 2 m ³	Up to 5 m ³ Up to 5 m ³ Up to 24 m ³				
Number of purification lines per purifier	1	1	2	2	2	
Number of reactor columns per line	1	1	1	1	2	
Number of reactor columns per nuitier	1	1	2	2	4	
Reactor capacity per purification line*	<u> </u>	1	2	2	4	
(O2) Oxygen	20	36 l	36 l	91 I	182 l	
(H2O) Moisture	900 q	1350 g	1350 g	4420 g	8840 q	
•	3	•	1350 g	4420 g	8840 g	
Regeneration	Automatic regeneration sequence					
Control unit	PLC - M. Braun	Siemens PLC				
Display	Large color touch panel	Large color touch panel				
Box pressure control	Automatic pressure control with foot switch (± 15mbar)					
Vacuum pump*	Rotary vane pump with 17 m ³ /h (10 CFM)					
Blower (50 Hz / 60 Hz)*	Variable speed up to 22 m ³ /h	Frequency controlled up to 88 m ³ /h		Frequency controlled up to 250 m³/h	Frequency controlled up to 500 m³/h	
Main and side piping	DN 40 ISO-KF					
Main and control valves	DN 40 ISO-KF					
Electrical (FLA) (without options)	Stainless steel 1.4301 (SUS 304)				
Cooling water (optional)	-	Optional: 2 bars max., (2-5 l/min)				
Regeneration gas	N2/H2 mix. or Ar/H2 mix. (H2 2-10 %)					
Working gas	Nitrogen, Argon or Helium					
Size in mm (LxWxH)	472 x 459 x 705	820 x 600 x 848	820 x 600 x 848	730 x 980 x 2040	1050 x 1230 x 2190	
Weight	50 kg (without vacu- um pump)	151 kg (without vacu- um pump)	171 kg (without vacu- um pump)	475 kg (without vacu- um pump)	855 kg (without vacu-	
Optional feature	Moisture and oxygen analyzer					
Optional feature	ECO Mode	ECO Mode				
Optional feature	Solvent vapor removal					
Optional feature	-	Regenerable solvent vapor removal				
Optional feature	-	Recirculation chiller for optimal working environment (RCC)				
Optional feature	Dry pump upgrade		, , , , , , , , , , , , , , , , , , , ,	,		
Optional feature w/ MBRAUN glovebox	Box purge function	Automatic box purge unit				
Optional feature w/ MBRAUN glovebox	Antechamber automatic (time controlled)	Antechamber automatic pressure controlled				
Optional feature w/ MBRAUN glovebox	Freezer	Freezer and box cooling	1			

^{*} Technical note: dependent upon operating conditions.

Solvent Traps

DESCRIPTION SOLVENT FILTER MB-BF

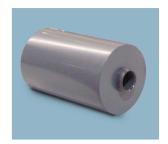
- Integrated into the glovebox (instead of the outer dust filters)
- Loading: Charcoal
- Easy exchange of loading
- Capacity*: 100 g solvent vapour
- Integrated dust filter HEPA H13

DESCRIPTION SOLVENT TRAP MB-LMF

- Integrated into the purifier unit or stand-alone
- Easy exchange of loading with bypass hand valves linked to the vacuum pump
- Loading: Charcoal
- Capacity*: 500 g solvent vapour

DESCRIPTION REGENERABLE SOLVENT TRAP MB-LMF-REG (INTEGRATED INTO THE GAS PURIFIER UNIT)

- Integrated into the purifier unit or stand-alone
- Regeneration programm PLC-operated
- Loading: Molecular sieve
- Capacity*: about 810 g solvent vapour





Accessories and Options

SENSORS FOR:

- Oxygen
- Moisture
- Solvents
- CO₂

FEEDTHROUGHS FOR:

- Liquid, gas, vacuum
- Cables (power supply, signal...)
- **USB** and other connectors
- Fiber optic

SPECIAL EQUIPMENT FOR GLOVEBOXES:

- Cold well

















Standard Antechambers

DESCRIPTION	SIZE	COMMENTS	
Main antechamber, cylindrical volume: 72 l	Ø 390 mm L: 600 mm	Can be mounted on right or left end panel, length can be modified on request	
Mini antechamber, cylindrical volume: 7 l	Ø 150 mm L: 400 mm	Can be mounted on right or left end panel, length can be modified on request	
Round T-shaped antechamber volume: 75 /100	Ø 390 mm L: 600 / 800 mm		
Square Antechamber volume: 16 l / 36 l	W: 200 mm H: 200 mm L: 400 mm or W: 300 mm H: 300 mm L: 400 mm	Can be mounted on right or left end panel	
Square L-shaped antechamber volume: 36 l	W: 300 mm H: 300 mm L: 400 mm	Can be mounted on right or left end panel	
Square T-shaped antechamber volume: 54 / 72	W: 300 mm H: 300 mm L: 600 / 800 mm		







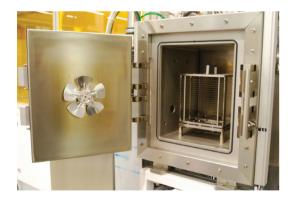


Standard Ovens

NAME	DESCRIPTION	
MB-VOH-Mini	Stand alone controller Vacuum heating Maximum temperature: 150 °C Ø 150 mm L: 400 mm	
MB-H-V-150-390	Stand alone controller Vacuum heating Maximum temperature: 150 °C Ø 390 mm L: 600 mm	
MB-H-V-250-390-W	PLC-operated Vacuum heating Maximum temperature: 250 °C Ø 390 mm L: 600 mm Water cooled	X I I I I I I I I I I I I I I I I I I I
MB-H-V-600-390-W	PLC-operated Vacuum heating Maximum temperature: 600 °C Ø 390 mm L: 600 mm Water cooled	

MORE OVENS AVAILABLE:

- Convection ovens
- Up to 2200 °C (under vacuum)
- Large volume ovens









Examples of Equipment Integration

THIN FILM DEPOSITION SYSTEMS:

- Cylindrical or square antechamber
- Fully integrated in the glovebox
- Thermal, organic, e-beam, sputtering sources
- Cryo, turbo pumps
- Controllers and measurement devices

ENCAPSULATION SOLUTIONS:

- **UV Press**
- **UV** Curing
- **Vacupress**
- Automatic dispensing robots

LAMINAR FLOW:

- **UDF**
- Laminar flow enclosure: class 1 (according US-FED Standard 209E) or particle class 2 (according ISO 14644-1)

SUBSTRAT PRE-TREATMENT OR CURING:

- **UV-Clean**
- Plasma cleaning
- Hot plates for ambient and vacuum
- Cryo, turbo pumps

BATTERY:

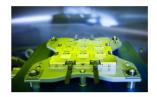
- **Electrolyte Filling**
- **Contact Welding**
- **Electrode Punching**

OTHER SOLUTIONS:

- Convection oven
- **Automation**
- **Solutions for Additive Manufacturing**











M. Braun Inertgas-Systeme GmbH (Headquarters) Dieselstr. 31 • D-85748 Garching • Germany Phone: +49 89 32669-0 • Fax: +49 89 32669-105

Web: www.mbraun.de E-Mail Sales: info@mbraun.de E-Mail Service: service@mbraun.de

Web: www.mbraunusa.com E-Mail Sales: info@mbraunusa.com E-Mail Service: service@mbraunusa.com

Ground floor of building #1 • No. 145 Jintang Road Tangzhen, Pudong, Shanghai • 201201 • P.R.China Phone: + 86 21 5032 02 57 • Fax: + 86 21 5032 02 29 Web: www.mbraunchina.com
E-Mail: info@mbraunchina.com

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